

# Vacuum Soldering System for processing of 300mmx300mm substrates - also for contaminating processes



Technical and design changes reserved

- For substrate size up to 300mm x 300mm
- Ramp up rate up to 150 K/min
- Control **SIMATIC**® with 7" touch panel
- Vacuum up to 10<sup>-3</sup> hPa (opt. 10<sup>-6</sup> hPa)
- Process gas line with MFC for N<sub>2</sub>
- Temperature up to 450 °C (opt. up to 650 °C)

## FEATURES

- Precise ramp up and fast ramp down rates
- Up to 4 gas lines (MFC)
- Heated by Infrared lamps
- 50 programs with 50 steps each
- Top and bottom heating (selection by Software)
- Small foot print
- 3 heating zones programmable

## APPLICATION

Reflow Solder Processes with or without vacuum up to 10<sup>-6</sup> hPa. Easy profiling by using a SIMATIC controller with WIN based software. Perfect lab tool and also for production on a low cost base. High production output. A remote control can be adjusted and the system can easily integrated into a production line.

- Reflow Solder Processes with flux
- Operation with inert gas, Oxygen, Forming gas, Formic Acid
- Lead and Lead-free SMT reflow
- Resistor paste firing

Tel: +(49)(0)8441-787663

Fax: +(49)(0)8441-787664



- Vacuum Solder System
- Programmable temperature profiles
- Record of process data
- Process in different gas atmospheres



#### **Vacuum Process Oven**

The **VSS-300** Reflow Solder System is an excellent tool for various solder processes up to 300 mm diameter wafer or 300 mm x 300 mm substrate size and 50 mm height (**Option: EH with 120 mm height.**)

Some examples for applications:

Laboratory furnace for all kind of developers implementing and researching new processes, prototype research, environmental research purposes and for small pre-series or series.

#### **PROCESS GASES**

The VSS-300 can be used with standard process gases, like Nitrogen, Oxygen, Forming Gas. The chamber is sealed and can easily be cleaned.

#### GAS FLOW CONTROL

One gas line with Mass Flow Controller (MFC) for Nitrogen(5 nlm = norm liter per minute) is default, three more gas lines (Option: MFC) are possible.

#### **VACUUM**

The system is vacuum capable of up to  $10^{-3}$  hPa (optionally up to  $10^{-6}$  hPa).

#### **HEATING**

The maximal achievable temperature is 400°C (opt. 650°C). Key features are precisely controlled fast rampup (150K/min) and excellent ramp-down rates (depend on temperature and loading).

## TEMPERATURE DISTRIBUTION

The VSS-300 allows an excellent temperature distribution and homogeneity. Optionally a graphite susceptor can be inserted on the quartz bottom plate.

#### **PROGRAMMING**

The VSS-300 is controlled by SIMATIC SPS controller. A 7" touch panel allows a very comfortable programming and control of the process. There can be saved up to 50 programs with 50 steps each



(unlimited programs can be down- and uploaded from an external data storage).

#### PROCESS CONTROL

The software allows the permanent monitoring, readout and analysis of
>temperature
>process gas flow
>cooling water level status
>pressure value and status

#### **COOLING PROCESS**

The hot plate is active cooled with homogenous cooling from both sides.

#### **OTHERS**

An interlock function as well as an Emergency-OFF-Button (EMO) are default.

#### **SPECIAL**

This oven can also be integrated into a production line. The chamber open/close is realized by push button operation.



## SPECIFICATION

Max. part size

Chamber material

Chamber height

Vacuum capability

Temperature max.

Temp. uniformity

Heating

Ramp up rate

Ramp down rate

Flow Controller

Controller

Chamber cooling

Substrate Cooling

300 mm dia. or 300 mm x 300 mm

Aluminium chamber (chamber area: 350 mm x 350 mm)

inclusive quartz glass bottom plate

50 mm (optional: 120 mm)

Up to 10<sup>-3</sup> hPa (optional up to 10<sup>-6</sup> hPa)

450 °C (higher temp. on request)

≤ 1% of set temperature (on a 200 mm wafer)

(e.g. +/- 3K @ 300 °C)

Bottom Heating: Infrared lamps cross aligned (18 kW)

150K/min

T= 450°C > 200°C: 90 K/min, T= 200°C > 100°C: 60K /min

One Mass Flow Controller for 5 nlm (=norm liter per minute)

as default, up to 3 more MFCs are available as option

SIMATIC® 50 programs with 50 steps each

By external water cooling system

By Nitrogen Gas

## TECHNICAL DATA

Dimension oven

Weight

Electrical connection

550 mm x 690 mm x 830 mm (W x D x H)

105 kg (estimated)

Tel: +(49)(0)8441-787663

Fax: +(49)(0)8441-787664

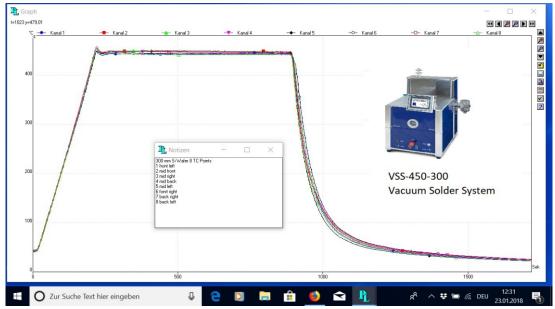
400/230V, 18 kW



## OPTIONS

| Formic Acid module (Module with Vessel for using Formic acid) with gas line            |
|--|
| Flux trap  |
| Additional gas line with Mass Flow controller (total: max 4 gas lines)                 |
| Lift Pins (on request)   |
| Chamber height 120mm with viewing window (60mm diameter)                               |
| Additional thermocouple to measure on device (plugged in chamber)                      |
| for external measurement tool (max. 4)   |
| Top Heat in cover  |
| Vacuum basic for vacuum up to 3 hPa incl. vacuum sensor and valve (excl. pump)         |
| Vacuum comfort for vacuum up to $10^{-3}$ hPa incl. vacuum sensor and valve (excl. p.) |
| Tubing made of VCR   |
| Serial interface between VSS system and external PC                                    |
| Remote control of top cover opening and closing  |
| Floor model with cabinet and integrated Universal Heat Exchanger (UHE)                 |
|  |

We offer a lot of different kind of closed loop water coolers and different pumps from e.g. Pfeiffer, Edwards, Leybold, Agilent. We recommend the correct configuration for your system.



Tel: +(49)(0)8441-787663

Fax: +(49)(0)8441-787664